

## SiC mesoporous membranes for sulfuric acid decomposition at high temperatures in the iodine-sulfur process

### Electronic supplementary information

Xin Yu,<sup>a</sup> Qing Wang,<sup>a</sup> Hiroki Nagasawa,<sup>a</sup> Masakoto Kanezashi,<sup>a</sup> and Toshinori Tsuru<sup>a\*</sup>

<sup>a</sup> Department of Chemical Engineering, Graduate School of Engineering, Hiroshima University, 1-4-1 Kagamiyama, Higashi-Hiroshima 739-8527, Japan

Corresponding author. Department of Chemical Engineering, Graduate School of Engineering, Hiroshima University, 1-4-1 Kagamiyama, Higashi-hiroshima 739-8527, Japan.

*E-mail address:* [tsuru@hiroshima-u.ac.jp](mailto:tsuru@hiroshima-u.ac.jp)

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#### ESI-1

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### Hydrothermal and chemical stability test for metal oxide

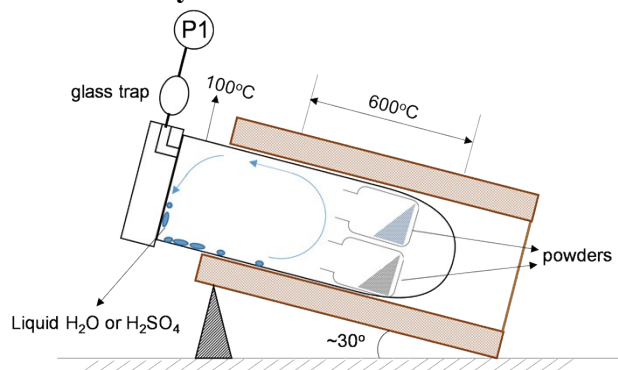


Fig. S1. Schematic diagram of the homemade device for the exposure of powders under H<sub>2</sub>O or H<sub>2</sub>SO<sub>4</sub> vapor. P1 is an automatic exhaust valve used to keep the closed system under a safe pressure of 1 bar. Liquid H<sub>2</sub>O or H<sub>2</sub>SO<sub>4</sub> can follow the cycles: vapor at 600 °C.

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ESI-2

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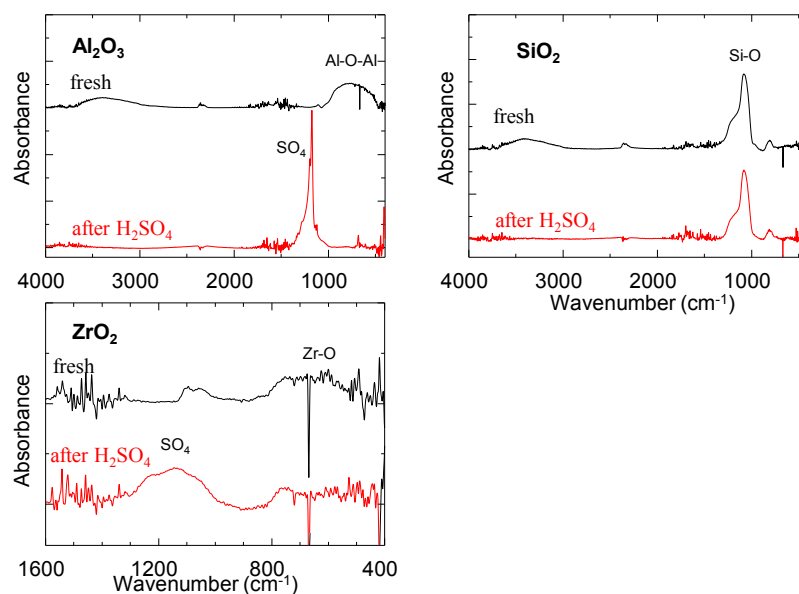


Fig. S2. FTIR spectra of  $\alpha\text{-Al}_2\text{O}_3$ ,  $\text{SiO}_2$  and  $\text{SiO}_2\text{-ZrO}_2$  before and after  $\text{H}_2\text{SO}_4$  exposure at 600 °C were investigated via ATR-FTIR (FT/IR-4100, Jasco, Japan) using an MCT detector cooled with liquid nitrogen. S-O peaks in  $\text{Al}_2\text{O}_3$ , and  $\text{ZrO}_2$  powders are cited from references.<sup>4, 5</sup>

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ESI-3

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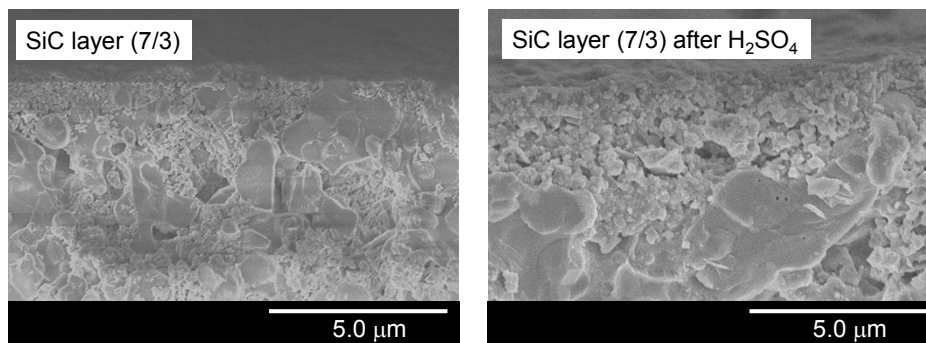


Fig. S3. Cross-section of  $\text{Al}_2\text{O}_3$  layer ( $\text{SiO}_2\text{-ZrO}_2=7/3$ ) and SiC layer ( $\text{SiO}_2\text{-ZrO}_2=7/3$ ) before and after  $\text{H}_2\text{SO}_4$  exposure.

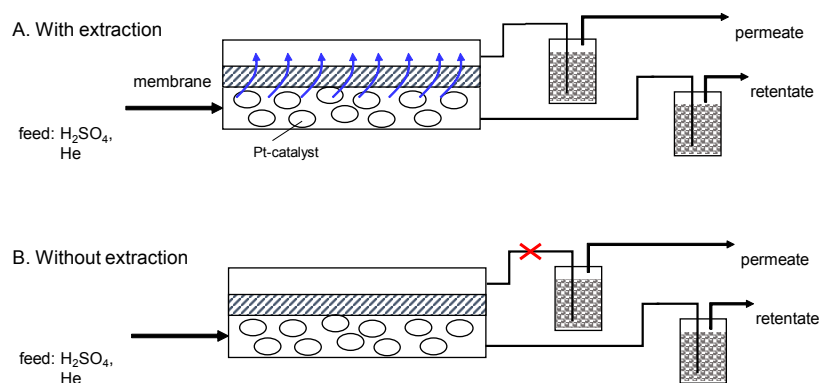


Fig. S4. Flow sheet of the membrane reactors with or without extraction for  $\text{H}_2\text{SO}_4$  decomposition.

#### References.

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